

Jun-Bo Yoon

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165
papers

3,275
citations

31
h-index

51
g-index

198
ext. papers

3,838
ext. citations

5.7
avg, IF

5.09
L-index

#	Paper	IF	Citations
165	A robust superhydrophobic and superoleophobic surface with inverse-trapezoidal microstructures on a large transparent flexible substrate. <i>Soft Matter</i> , 2010 , 6, 1401	3.6	290
164	A sub-1-volt nanoelectromechanical switching device. <i>Nature Nanotechnology</i> , 2013 , 8, 36-40	28.7	135
163	Microlens array diffuser for a light-emitting diode backlight system. <i>Optics Letters</i> , 2006 , 31, 3016-8	3	126
162	Self-cleaning hybrid energy harvester to generate power from raindrop and sunlight. <i>Nano Energy</i> , 2015 , 12, 636-645	17.1	118
161	Fabrication and characterization of a nanoelectromechanical switch with 15-nm-thick suspension air gap. <i>Applied Physics Letters</i> , 2008 , 92, 103110	3.4	112
160	Performance-enhanced triboelectric nanogenerator enabled by wafer-scale nanogrates of multistep pattern downscaling. <i>Nano Energy</i> , 2017 , 35, 415-423	17.1	101
159	"Lock-and-key" geometry effect of patterned surfaces: wettability and switching of adhesive force. <i>Small</i> , 2009 , 5, 90-4	11	97
158	CMOS-compatible surface-micromachined suspended-spiral inductors for multi-GHz silicon RF ICs. <i>IEEE Electron Device Letters</i> , 2002 , 23, 591-593	4.4	89
157	Shape-controlled, high fill-factor microlens arrays fabricated by a 3D diffuser lithography and plastic replication method. <i>Optics Express</i> , 2004 , 12, 6366-71	3.3	82
156	Surface micromachined solenoid on-Si and on-glass inductors for RF applications. <i>IEEE Electron Device Letters</i> , 1999 , 20, 487-489	4.4	81
155	NEMS switch with 30 nm-thick beam and 20 nm-thick air-gap for high density non-volatile memory applications. <i>Solid-State Electronics</i> , 2008 , 52, 1578-1583	1.7	74
154	3-D construction of monolithic passive components for RF and microwave ICs using thick-metal surface micromachining technology. <i>IEEE Transactions on Microwave Theory and Techniques</i> , 2003 , 51, 279-288	4.1	69
153	Simple liquid crystal display backlight unit comprising only a single-sheet micropatterned polydimethylsiloxane (PDMS) light-guide plate. <i>Optics Letters</i> , 2007 , 32, 2665-7	3	61
152	A simple and effective lift-off with positive photoresist. <i>Journal of Micromechanics and Microengineering</i> , 2005 , 15, 2136-2140	2	60
151	Spontaneous Lamellar Alignment in Thickness-Modulated Block Copolymer Films. <i>Advanced Functional Materials</i> , 2009 , 19, 2584-2591	15.6	59
150	60-GHz CPW-fed post-supported patch antenna using micromachining technology. <i>IEEE Microwave and Wireless Components Letters</i> , 2005 , 15, 635-637	2.6	54
149	Experimental analysis of the effect of metal thickness on the quality factor in integrated spiral inductors for RF ICs. <i>IEEE Electron Device Letters</i> , 2004 , 25, 76-79	4.4	47

148	Hermetically Sealed Inductor-Capacitor (LC) Resonator for Remote Pressure Monitoring. <i>Japanese Journal of Applied Physics</i> , 1998 , 37, 7124-7128	1.4	47
147	Optically selective microlens photomasks using self-assembled smectic liquid crystal defect arrays. <i>Advanced Materials</i> , 2010 , 22, 2416-20	24	44
146	A simple and effective fabrication method for various 3D microstructures: backside 3D diffuser lithography. <i>Journal of Micromechanics and Microengineering</i> , 2008 , 18, 125015	2	44
145	Nanoelectromechanical (NEM) relays integrated with CMOS SRAM for improved stability and low leakage 2009 ,		43
144	Versatile Transfer of an Ultralong and Seamless Nanowire Array Crystallized at High Temperature for Use in High-Performance Flexible Devices. <i>ACS Nano</i> , 2017 , 11, 1520-1529	16.7	41
143	A thermal inkjet printhead with a monolithically fabricated nozzle plate and self-aligned ink feed hole. <i>Journal of Microelectromechanical Systems</i> , 1999 , 8, 229-236	2.5	40
142	A one-step route to a perfectly ordered wafer-scale microbowl array for size-dependent superhydrophobicity. <i>Small</i> , 2008 , 4, 211-6	11	37
141	Monolithic Fabrication of Electroplated Solenoid Inductors Using Three-Dimensional Photolithography of a Thick Photoresist. <i>Japanese Journal of Applied Physics</i> , 1998 , 37, 7081-7085	1.4	36
140	Metal-oxide-semiconductor field effect transistor humidity sensor using surface conductance. <i>Applied Physics Letters</i> , 2012 , 100, 101603	3.4	35
139	A high fill-factor infrared bolometer using micromachined multilevel electrothermal structures. <i>IEEE Transactions on Electron Devices</i> , 1999 , 46, 1489-1491	2.9	35
138	Industrial Grade, Bending-Insensitive, Transparent Nanoforce Touch Sensor via Enhanced Percolation Effect in a Hierarchical Nanocomposite Film. <i>Advanced Functional Materials</i> , 2018 , 28, 1804721	15.6	35
137	High throughput ultralong (20 cm) nanowire fabrication using a wafer-scale nanograting template. <i>Nano Letters</i> , 2013 , 13, 3978-84	11.5	33
136	Electrowetting on a polymer microlens array. <i>Langmuir</i> , 2010 , 26, 12443-7	4	32
135	Fabrication of polymeric large-core waveguides for optical interconnects using a rubber molding process. <i>IEEE Photonics Technology Letters</i> , 2000 , 12, 62-64	2.2	32
134	Analytical modeling and thermodynamic analysis of robust superhydrophobic surfaces with inverse-trapezoidal microstructures. <i>Langmuir</i> , 2010 , 26, 17389-97	4	30
133	One-chip electronic detection of DNA hybridization using precision impedance-based CMOS array sensor. <i>Biosensors and Bioelectronics</i> , 2010 , 26, 1373-9	11.8	30
132	An Extremely Low Contact-Resistance MEMS Relay Using Meshed Drain Structure and Soft Insulating Layer. <i>Journal of Microelectromechanical Systems</i> , 2011 , 20, 204-212	2.5	29
131	High-Performance Copper Oxide Visible-Light Photodetector via Grain-Structure Model. <i>Scientific Reports</i> , 2019 , 9, 7334	4.9	28

130	An Electrostatically Actuated Stacked-Electrode MEMS Relay With a Levering and Torsional Spring for Power Applications. <i>Journal of Microelectromechanical Systems</i> , 2012 , 21, 1209-1217	2.5	28
129	A conventional route to scalable morphology-controlled regular structures and their superhydrophobic/hydrophilic properties for biochips application. <i>Lab on A Chip</i> , 2009 , 9, 2140-4	7.2	28
128	MEMS-Based Tunable LC Bandstop Filter With an Ultra-Wide Continuous Tuning Range. <i>IEEE Microwave and Wireless Components Letters</i> , 2009 , 19, 710-712	2.6	25
127	Parallel-Plate MEMS Variable Capacitor With Superior Linearity and Large Tuning Ratio Using a Levering Structure. <i>Journal of Microelectromechanical Systems</i> , 2011 , 20, 1345-1354	2.5	24
126	Liquid-based electrostatic energy harvester with high sensitivity to human physical motion. <i>Smart Materials and Structures</i> , 2011 , 20, 125012	3.4	24
125	A simple breathing rate-sensing method exploiting a temporarily condensed water layer formed on an oxidized surface. <i>Applied Physics Letters</i> , 2015 , 106, 053701	3.4	22
124	A CMOS label-free DNA sensor using electrostatic induction of molecular charges. <i>Biosensors and Bioelectronics</i> , 2012 , 31, 343-8	11.8	22
123	3-terminal nanoelectromechanical switching device in insulating liquid media for low voltage operation and reliability improvement 2009 ,		22
122	Monolithic high-Q overhang inductors fabricated on silicon and glass substrates		21
121	A Complementary Dual-Contact MEMS Switch Using a Zipping Technique. <i>Journal of Microelectromechanical Systems</i> , 2014 , 23, 710-718	2.5	20
120	Complementary Dual-Contact Switch Using Soft and Hard Contact Materials for Achieving Low Contact Resistance and High Reliability Simultaneously. <i>Journal of Microelectromechanical Systems</i> , 2013 , 22, 846-854	2.5	20
119	CMOS capacitive biosensor with enhanced sensitivity for label-free DNA detection 2012 ,		19
118	Use of a columnar metal thin film as a nanosieve with sub-10 nm pores. <i>Advanced Materials</i> , 2012 , 24, 4408-13	24	19
117	An ultra-low voltage MEMS switch using stiction-recovery actuation. <i>Journal of Micromechanics and Microengineering</i> , 2013 , 23, 045022	2	19
116	Nanowire mechanical switch with a built-in diode. <i>Small</i> , 2010 , 6, 1197-200	11	18
115	Mechanically Operated Random Access Memory (MORAM) Based on an Electrostatic Microswitch for Nonvolatile Memory Applications. <i>IEEE Transactions on Electron Devices</i> , 2008 , 55, 2785-2789	2.9	18
114	>1000-Fold Lifetime Extension of a Nickel Electromechanical Contact Device via Graphene. <i>ACS Applied Materials & Interfaces</i> , 2018 , 10, 9085-9093	9.5	17
113	Material-Independent Nanotransfer onto a Flexible Substrate Using Mechanical-Interlocking Structure. <i>ACS Nano</i> , 2018 , 12, 4387-4397	16.7	17

112	Fabrication of a uniform microlens array over a large area using self-aligned diffuser lithography (SADL). <i>Journal of Micromechanics and Microengineering</i> , 2012 , 22, 045002	2	16
111	Actively transparent display with enhanced legibility based on an organic light-emitting diode and a cholesteric liquid crystal blind panel. <i>Optics Express</i> , 2013 , 21, 10358-66	3.3	15
110	Silicon Photonic Wire Filter Using Asymmetric Sidewall Long-Period Waveguide Grating in a Two-Mode Waveguide. <i>IEEE Photonics Technology Letters</i> , 2008 , 20, 520-522	2.2	15
109	Batch-fabricated CO gas sensor in large-area (8-inch) with sub-10 mW power operation. <i>Sensors and Actuators B: Chemical</i> , 2019 , 289, 153-159	8.5	14
108	A Highly Reliable MEMS Relay With Two-Step Spring System and Heat Sink Insulator for High-Power Switching Applications. <i>Journal of Microelectromechanical Systems</i> , 2016 , 25, 217-226	2.5	14
107	Multi-resonant energy harvester exploiting high-mode resonances frequency down-shifted by a flexible body beam. <i>Applied Physics Letters</i> , 2012 , 101, 123903	3.4	14
106	Edge-lit LCD backlight unit for 2D local dimming. <i>Optics Express</i> , 2018 , 26, 20802-20812	3.3	14
105	. <i>Journal of Microelectromechanical Systems</i> , 2015 , 24, 1495-1502	2.5	13
104	Stress-engineered palladium nanowires for wide range (0.1%-3.9%) of H detection with high durability. <i>Nanoscale</i> , 2019 , 11, 16317-16326	7.7	12
103	A mechanical and electrical transistor structure (METS) with a sub-2 nm nanogap for effective voltage scaling. <i>Nanoscale</i> , 2014 , 6, 7799-804	7.7	12
102	Nanotransplantation Printing of Crystallographic-Orientation-Controlled Single-Crystalline Nanowire Arrays on Diverse Surfaces. <i>ACS Nano</i> , 2017 , 11, 11642-11652	16.7	12
101	Fabrication of three-dimensional SiC-based ceramic micropatterns using a sequential micromolding-and-pyrolysis process. <i>Microelectronic Engineering</i> , 2006 , 83, 2475-2481	2.5	12
100	Transparent conducting hybrid thin films fabricated by layer-by-layer assembly of single-wall carbon nanotubes and conducting polymers. <i>Applied Physics A: Materials Science and Processing</i> , 2012 , 108, 305-311	2.6	11
99	Multilevel microstructure fabrication using single-step 3D photolithography and single-step electroplating 1998 ,		11
98	Geometrically Structured Nanomaterials for Nanosensors, NEMS, and Nanosieves. <i>Advanced Materials</i> , 2020 , 32, e1907082	24	10
97	Ultra-low voltage MEMS switch using a folded hinge structure. <i>Micro and Nano Systems Letters</i> , 2014 , 2,	2	10
96	Electrostatic micro-actuator with a pre-charged series capacitor: modeling, design, and demonstration. <i>Journal of Micromechanics and Microengineering</i> , 2014 , 24, 065012	2	10
95	High-performance hybrid complementary logic inverter through monolithic integration of a MEMS switch and an oxide TFT. <i>Small</i> , 2015 , 11, 1390-5	11	10

94	An insulating liquid environment for reducing adhesion in a microelectromechanical system. <i>Applied Physics Letters</i> , 2011 , 99, 113516	3.4	10
93	Modeling, Design, Fabrication, and Demonstration of a Digital Micromirror With Interdigitated Cantilevers. <i>Journal of Microelectromechanical Systems</i> , 2009 , 18, 1382-1395	2.5	10
92	A new monolithic microbiosensor for whole blood analysis. <i>Sensors and Actuators A: Physical</i> , 2002 , 95, 108-113	3.9	10
91	Fabrication of a membrane filter with controlled pore shape and its application to cell separation and strong single cell trapping. <i>Journal of Micromechanics and Microengineering</i> , 2015 , 25, 105007	2	9
90	An effective light-extracting microstructure for a single-sheet backlight unit for liquid crystal display. <i>Journal of Micromechanics and Microengineering</i> , 2012 , 22, 095006	2	9
89	Modeling, fabrication and demonstration of a rib-type cantilever switch with an extended gate electrode. <i>Journal of Micromechanics and Microengineering</i> , 2011 , 21, 115009	2	9
88	A 3-D planar microlens for an effective monolithic optical interconnection system. <i>IEEE Photonics Technology Letters</i> , 2006 , 18, 814-816	2.2	9
87	High-performance electroplated solenoid-type integrated inductor (SI/sup 2/) for RF applications using simple 3D surface micromachining technology		9
86	Chemo-Mechanically Operating Palladium-Polymer Nanograting Film for a Self-Powered H Gas Sensor. <i>ACS Nano</i> , 2020 ,	16.7	9
85	Use of nanoporous columnar thin film in the wafer-level packaging of MEMS devices. <i>Journal of Micromechanics and Microengineering</i> , 2010 , 20, 045002	2	8
84	A new approach to control a deflection of an electroplated microstructure: dual current electroplating methods. <i>Journal of Micromechanics and Microengineering</i> , 2013 , 23, 055016	2	7
83	Nanomechanical Encoding Method Using Enhanced Thermal Concentration on a Metallic Nanobridge. <i>ACS Nano</i> , 2017 , 11, 7781-7789	16.7	7
82	An autonomous CMOS hysteretic sensor for the detection of desorption-free DNA hybridization. <i>Biosensors and Bioelectronics</i> , 2011 , 26, 4591-5	11.8	7
81	A trans-scaled nanofabrication using 3D diffuser lithography, metal molding and nano-imprinting. <i>Journal of Micromechanics and Microengineering</i> , 2011 , 21, 045025	2	7
80	MEMS Variable Capacitor Actuated with an Electrically Floating Plate 2007 ,		7
79	3-D lithography and metal surface micromachining for RF and microwave MEMS		7
78	A Low Contact Resistance 4-Terminal Mems Relay: Theoretical Analysis, Design, and Demonstration. <i>Journal of Microelectromechanical Systems</i> , 2018 , 27, 497-505	2.5	6
77	An electrostatic micromechanical biosensor for electrical detection of label-free DNA. <i>Applied Physics Letters</i> , 2012 , 100, 163701	3.4	6

76	High performance microshutter device with space-division modulation. <i>Journal of Micromechanics and Microengineering</i> , 2010 , 20, 075030	2	6
75	Adhesion Force Change by Electrowetting on a Polymer Microlens Array. <i>Journal of Adhesion Science and Technology</i> , 2012 , 26, 2079-2086	2	6
74	56.2: A New Reflective-type Transparent Display Using Cholesteric Liquid Crystal. <i>Digest of Technical Papers SID International Symposium</i> , 2010 , 41, 838	0.5	6
73	Sloping profile and pattern transfer to silicon by shape-controllable 3-D lithography and ICP. <i>Sensors and Actuators A: Physical</i> , 2007 , 139, 281-286	3.9	6
72	A Dram-Like Mechanical Non-Volatile Memory 2007 ,		6
71	High-performance three-dimensional on-chip inductors fabricated by novel micromachining technology for RF MMIC		6
70	Integration of a Carbon Nanotube Network on a Microelectromechanical Switch for Ultralong Contact Lifetime. <i>ACS Applied Materials & Interfaces</i> , 2019 , 11, 18617-18625	9.5	5
69	Highly reliable MEMS relay with two-step spring system and heat sink insulator for power applications 2015 ,		5
68	Mechanical Reliability of a Digital Micromirror With Interdigitated Cantilevers. <i>Journal of Microelectromechanical Systems</i> , 2010 , 19, 1197-1206	2.5	5
67	Indium Tin Oxide (ITO) Transparent MEMS Switches 2009 ,		5
66	P-73: A Novel LCD Backlight Unit using a Light-guide Plate with High Fill-factor Microlens Array and a Conical Microlens Array Sheet. <i>Digest of Technical Papers SID International Symposium</i> , 2007 , 38, 465-468	0.5	5
65	Monolithic integration of 3-D electroplated microstructures with unlimited number of levels using planarization with a sacrificial metallic mold (PSMM) 1999 ,		5
64	Perfectly Aligned, Air-Suspended Nanowire Array Heater and Its Application in an Always-On Gas Sensor. <i>Advanced Functional Materials</i> , 2020 , 30, 2004448	15.6	5
63	A review of geometric and structural design for reliable flexible electronics. <i>Journal of Micromechanics and Microengineering</i> , 2021 , 31, 074001	2	5
62	. <i>Journal of Microelectromechanical Systems</i> , 2015 , 24, 1545-1556	2.5	4
61	Realization of Nanolene: A Planar Array of Perfectly Aligned, Air-Suspended Nanowires. <i>Small</i> , 2020 , 16, e1906845	11	4
60	Voltage-Controlled $\{V\}$ Response Tuning in a Parallel Plate MEMS Variable Capacitor. <i>Journal of Microelectromechanical Systems</i> , 2013 , 22, 1403-1413	2.5	4
59	. <i>Journal of Microelectromechanical Systems</i> , 2017 , 26, 1417-1427	2.5	4

58	Novel buried inverse-trapezoidal micropattern for dual-sided light extracting backlight unit. <i>Optics Express</i> , 2014 , 22, 32440-9	3.3	4
57	MEMS variable capacitor with superior linearity and large tuning ratio by moving the plate to the increasing-gap direction 2011 ,		4
56	High-Q, tunable-gap MEMS variable capacitor actuated with an electrically floating plate 2008 ,		4
55	A low loss MEMS transmission line with shielded ground		4
54	P-72: Ultra-thin Edge Type Single Sheet Backlight Unit for Seamless Two-dimensional Local Dimming. <i>Digest of Technical Papers SID International Symposium</i> , 2016 , 47, 1406-1408	0.5	4
53	Utilizing mechanical adhesion force as a high contact force in a MEMS relay. <i>Sensors and Actuators A: Physical</i> , 2021 , 331, 112894	3.9	4
52	Increasing Capacitance and Self-Resonant Frequency of the MEMS Switched Capacitor Using High- κ TiO ₂ and SU-8 Bridged Beam Structure. <i>Journal of Microelectromechanical Systems</i> , 2015 , 24, 1006-1015	2.5	3
51	Effect of excitation point on surface phonon fields in phononic crystals in real- and k-space. <i>Journal of Applied Physics</i> , 2015 , 117, 245308	2.5	3
50	Improvement of hot switching lifetime in MEMS DC switches using a drain voltage-sustaining capacitor 2013 ,		3
49	Fabrication of a large-scale Ni stamp using a multi-level SU-8 photoresist mold for advanced printed circuit board manufacturing. <i>Journal of Micromechanics and Microengineering</i> , 2011 , 21, 065026	2	3
48	Mass-Producible Polydimethylsiloxane (PDMS) Frontlight Unit (FLU) for Reflective Displays. <i>Journal of Display Technology</i> , 2011 , 7, 526-531		3
47	Exchangeable self-curable liquid gate dielectric embedded field effect transistor. <i>Applied Physics Letters</i> , 2010 , 97, 032112	3.4	3
46	Modeling, fabrication and demonstration of an electrostatic actuator with a coplanar pre-charged electrode. <i>Journal of Micromechanics and Microengineering</i> , 2011 , 21, 085012	2	3
45	Linearly variable inductor with RF MEMS switches to enlarge a continuous tuning range 2009 ,		3
44	Electrostatic digital micromirror using interdigitated cantilevers		3
43	First Lateral Contact Probing of 55- μm Fine Pitch Micro-Bumps. <i>Journal of Microelectromechanical Systems</i> , 2018 , 27, 1114-1123	2.5	3
42	Carbon nanotubes network contact lubrication for highly reliable MEMS switch 2017 ,		2
41	Highly aligned suspended nanowire array for self-heating type gas sensors 2017 ,		2

40	Realization of large-scale sub-10nm nanogratings using a repetitive wet-chemical oxidation and etching technique. <i>Micro and Nano Systems Letters</i> , 2017 , 5,	2	2
39	Ultra-Sensitive Strain Sensor Using High Density Self-Aligned Nano-Cracks 2020 ,		2
38	An investigation of surficial conduction heat loss in perfectly aligned micro-wire array. <i>Applied Physics Letters</i> , 2019 , 115, 131901	3-4	2
37	4-Terminal MEMS relay with an extremely low contact resistance employing a novel one-contact design 2017 ,		2
36	High-performance MEMS relay using a stacked-electrode structure and a levering and torsional spring for power applications 2012 ,		2
35	A Highly Flexible Superhydrophobic Microlens Array with Small Contact Angle Hysteresis for Droplet-Based Microfluidics 2009 ,		2
34	Performance comparison of 5GHz VCOs integrated by CMOS compatible high Q MEMS inductors		2
33	A low-voltage two-axis electromagnetically actuated micromirror with bulk silicon mirror plates and torsion bars		2
32	A high-performance MEMS transformer for silicon RF ICs		2
31	A surface-micromachined tunable microgyroscope		2
30	Fabrication of a Single Crystal Silicon Substrate for AM-LCD Using Vertical Etching of (110) Silicon. <i>Materials Research Society Symposia Proceedings</i> , 1995 , 377, 859		2
29	4 W Power MEMS Relay With Extremely Low Contact Resistance: Theoretical Analysis, Design and Demonstration. <i>Journal of Microelectromechanical Systems</i> , 2020 , 29, 1304-1313	2.5	2
28	Unconventional Use of a Photoresist as a Nitrogen Gas Generator Forming Transparent Dome-Shaped Microcavities. <i>Advanced Engineering Materials</i> , 2016 , 18, 559-566	3-5	2
27	Micro and Nanoelectromechanical Contact Switches for Logic, Memory, and Power Applications. <i>KAIST Research Series</i> , 2016 , 65-117		1
26	Self-Powered, Ultra-Reliable Hydrogen Sensor Exploiting Chemomechanical Nano-Transducer and Solar-Cell 2019 ,		1
25	2019 ,		1
24	Efforts toward ideal microelectromechanical switches 2017 ,		1
23	Three-dimensional (3-D) reshaping technique in MEMS devices by solely electrical control with ultrafine tuning resolution 2014 ,		1

22	Fast and robust cantilever switch with suppressed bouncing for ic applications 2011 ,		1
21	3.4: Invited Paper: A Novel Use of MEMS Switches in Driving AMOLED. <i>Digest of Technical Papers SID International Symposium</i> , 2008 , 39, 13	0.5	1
20	A New Three-Dimensional Lithography Using Polymer Dispersed Liquid Crystal (PDLC) Films		1
19	Micromachined CPW-fed suspended patch antenna for 77 GHz automotive radar applications 2005 ,		1
18	Micromachined CPW-fed suspended patch antenna for 77 GHz automotive radar applications		1
17	3D diffuser lithography: a novel method to fabricate various rounded microstructures		1
16	Self-assembled monolayer-assisted thin metal polishing for fabricating uniform 3D microstructures. <i>Journal of Micromechanics and Microengineering</i> , 2005 , 15, 1027-1032	2	1
15	High fill-factor micromirror array and its fabrication process		1
14	A disposable DNA sample preparation microfluidic chip for nucleic acid probe assay		1
13	Aligned CuO nanowire array for a high performance visible light photodetector.. <i>Scientific Reports</i> , 2022 , 12, 2284	4.9	1
12	Always-On Gas Sensors: Perfectly Aligned, Air-Suspended Nanowire Array Heater and Its Application in an Always-On Gas Sensor (Adv. Funct. Mater. 39/2020). <i>Advanced Functional Materials</i> , 2020 , 30, 2070264	15.6	1
11	P-67: Wide Bandwidth Reflective Microshutter Blind Panel for Transparent Organic Light-Emitting Diode Display. <i>Digest of Technical Papers SID International Symposium</i> , 2016 , 47, 1389-1391	0.5	1
10	P-70: Light Shifted Light-guide Plate for Simple Multi-view Spatial/Temporal Hybrid Autostereoscopic Display. <i>Digest of Technical Papers SID International Symposium</i> , 2016 , 47, 1399-1401	0.5	1
9	Mass-producible structural design and fabrication method for a slim light-guide plate having inverse-trapezoidal light out-couplers. <i>Journal of Micromechanics and Microengineering</i> , 2019 , 29, 03500 [†]		1
8	4 W Dual-Contact Material MEMS Relay with a Contact Force Maximizing Structure 2020 ,		1
7	A Proactive Plastic Deformation Method for Fine-Tuning of Metal-Based MEMS Devices After Fabrication. <i>Journal of Microelectromechanical Systems</i> , 2018 , 27, 1124-1134	2.5	1
6	Electro-Thermally Actuated Non-Volatile Mechanical Memory With CMOS-Level Operation Voltage and Low Contact Resistance. <i>Journal of Microelectromechanical Systems</i> , 2022 , 31, 87-96	2.5	0
5	Integration of Gold Nanoparticle-Carbon Nanotube Composite for Enhanced Contact Lifetime of Microelectromechanical Switches with Very Low Contact Resistance. <i>ACS Applied Materials & Interfaces</i> , 2021 , 13, 16959-16967	9.5	0

- 4 Nanowires: Realization of Nanolene: A Planar Array of Perfectly Aligned, Air-Suspended Nanowires (Small 13/2020). *Small*, **2020**, 16, 2070072 11
- 3 . *Journal of Microelectromechanical Systems*, **2016**, 25, 909-915 2.5
- 2 Densely-Packed Microbowl Array with Balanced Dielectrophoretic Forces for Single-Cell Microarray. *Materials Research Society Symposia Proceedings*, **2009**, 1222, 1
- 1 Touch Sensors: Industrial Grade, Bending-Insensitive, Transparent Nanoforce Touch Sensor via Enhanced Percolation Effect in a Hierarchical Nanocomposite Film (Adv. Funct. Mater. 42/2018). *Advanced Functional Materials*, **2018**, 28, 1870305 15.6